

WHAT IS CLAIMED IS:

1. A deposited film forming apparatus comprising a power applying electrode disposed above a flat plate ~~type~~ base member grounded, in a vacuum chamber, and a power source for supplying a power to the power applying electrode,

the deposited film forming apparatus being constructed to supply the power from the power source to the power applying electrode so as to generate a plasma in a discharge space between the power applying electrode and a substrate disposed in opposition to the power applying electrode in the vacuum chamber and serving as an electrode in a pair with the power applying electrode, thereby decomposing a source gas introduced into the vacuum chamber to form a deposited film on the substrate,

wherein the power applying electrode is fixed to the base member with the power applying electrode being ~~isolated~~ from the base member.

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2. The deposited film forming apparatus according to Claim 1, comprising a mechanism for conveying the substrate.

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3. The deposited film forming apparatus according to Claim 2, wherein the mechanism for conveying the substrate is of a roll-to-roll system, and the

deposited film is formed while the substrate is conveyed thereby.

4. The deposited film forming apparatus according  
5 to Claim 1, wherein the distance between the power  
applying electrode and the substrate is 5 mm to 20 mm.

5. The deposited film forming apparatus according  
to Claim 1, wherein the power applying electrode is  
10 fixed to the base member with an electrically  
insulating, fastening member.

6. The deposited film forming apparatus according  
to Claim 1, wherein the base member is disposed around  
15 the power applying electrode and the power applying  
electrode is fastened by the base member.

7. The deposited film forming apparatus according  
to Claim 1, wherein the base member is held between and  
20 fastened by the power applying electrode and a power  
introducing portion penetrating the base member in  
order to supply the power to the power applying  
electrode.

*no rigid member  
holding electrode*

25 8. The deposited film forming apparatus according  
to Claim 1, wherein the power applying electrode and  
the base member are fixed with an electrically

insulating adhesive.

9. The deposited film forming apparatus according to Claim 1, wherein the power applying electrode is  
5 fixed to the base member at an end portion of the power applying electrode.

10. The deposited film forming apparatus according to Claim 1, wherein the power applying electrode is fixed to the base member at a position  
10 effective to suppress deformation of the power applying electrode.

11. The deposited film forming apparatus according to Claim 1, wherein an electrically  
15 insulating spacer is placed between the power applying electrode and the base member.

12. The deposited film forming apparatus according to Claim 1, wherein an electrically  
20 insulating material is filled between the power applying electrode and the base member.

13. The deposited film forming apparatus according to Claim 1, wherein the distance  $s$  [mm]  
25 between the power applying electrode and the base member satisfies the relation of  $s \leq k/P$ , where  $P$  [Pa]

is a pressure in the vacuum chamber during formation of the deposited film and  $k$  is a constant of 1500 [Pa·mm].

14. A method of forming a deposited film  
5 comprising using the deposited film forming apparatus  
as set forth in any one of Claims 1 to 13.